L Number	Hits	Search Text	DB	Time stamp
-	4	(("5939236") or ("6261743")).PN.	USPAT;	2003/05/20 13:34
		,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,	US-PGPUB;	
			EPO; JPO;	İ
			DERWENT	1
_	29335	antireflective antireflection	USPAT;	2003/05/20 13:35
	2,555	anti-reflective anti-reflection anti adj	US-PGPUB;	2003/03/20 13.33
		reflective anti adj reflection	EPO; JPO;	
		refrective and adj refrection	DERWENT	
	29206	wasin adi bindan	1	2003/05/20 13:52
· .	29200	resin adj binder	USPAT;	2003/03/20 13:32
			US-PGPUB;	
			EPO; JPO;	
			DERWENT	
-	2725	acid adj generator	USPAT;	2003/05/20 13:38
			US-PGPUB;	
			EPO; JPO;	
			DERWENT	
-	1194	thermal adj2 generator	USPAT;	2003/05/20 13:38
,			US-PGPUB;	
			EPO; JPO;	
			DERWENT	
-	. 2171	(photoacid photo-acid photo adj acid) adj2	USPAT;	2003/05/20 13:39
		generator	US-PGPUB;	
			EPO; JPO;	
			DERWENT	
-	6832	pag!	USPAT;	2003/05/20 13:39
			US-PGPUB;	
			EPO; JPO;	
			DERWENT	
_	55	PAVELCHEK-Ein. PAVELCHEK-EDWARDin.	USPAT;	2003/05/20 13:43
		PAVELCHEK-EDWARD-Kin. PAVELCHEK-E-Kin.	US-PGPUB;	2000,00,20 13.13
		PAVELCHEKin. DOCANTO-Min. DOCANTOin.	EPO; JPO;	
		DOCANTO-MANUELin.	DERWENT	
_	930	tarc! barc!	USPAT;	2003/05/20 13:50
			US-PGPUB;	2000,00,20 20.00
			EPO; JPO;	
			DERWENT	
_	4475	(arc!) near (coating film layer material)	USPAT;	2003/05/20 13:51
	11.0	(did.) hear (codding lilm layer macerial)	US-PGPUB;	2003/03/20 13.31
			EPO; JPO;	
			DERWENT	
_	16	((antireflective antireflection		2003/05/20 14:00
_	10	anti-reflective anti-reflection anti adj	USPAT; US-PGPUB;	2003/03/20 14:00
		reflective anti adj reflection) (tarc!	EPO; JPO;	
			DERWENT	
		barc!) ((arc!) near (coating film layer material))) same (resin adj binder) same	DERWENT	
		((acid adj generator) (thermal adj2 generator)) same (((photoacid photo-acid	İ	
_	23	photo adj acid) adj2 generator) pag!)	IICDAM.	2003/05/20 14:01
'	23	((antireflective antireflection	USPAT; US-PGPUB;	2003/03/20 14:01
		anti-reflective anti-reflection anti adj		
		reflective anti adj reflection) (tarc!	EPO; JPO;	
		barc!) ((arc!) near (coating film layer	DERWENT	1
		material))) same (resin adj binder) same		
		(acid (thermal adj2 generator)) same		
		(((photoacid photo-acid photo adj acid)		
		adj2 generator) pag!)	1	1

-	7	(((antireflective antireflection anti-reflective anti-reflection anti adj	USPAT; US-PGPUB;	2003/05/20 13:58
1		reflective anti adj reflection) (tarc!	EPO; JPO;	
		barc!) ((arc!) near (coating film layer	DERWENT	
		material))) same (resin adj binder) same		
		(acid (thermal adj2 generator)) same		
		(((photoacid photo-acid photo adj acid)		
		adj2 generator) pag!)) not		
		(((antireflective antireflection anti-reflective anti-reflection anti adj		
		reflective anti adj reflection) (tarc!		
		barc!) ((arc!) near (coating film layer		
		material))) same (resin adj binder) same		
j		((acid adj generator) (thermal adj2		
		generator)) same (((photoacid photo-acid		
		<pre>photo adj acid) adj2 generator) pag!))</pre>		
-	8103	antihalation anti-halation anti adj	USPAT;	2003/05/20 14:00
		halation	US-PGPUB;	
			EPO; JPO; DERWENT	
_	8	((antihalation anti-halation anti adj	USPAT;	2003/05/20 14:01
		halation)) same (resin adj binder) same	US-PGPUB;	1000,00,20 14.01
		(acid (thermal adj2 generator)) same	EPO; JPO;	
		(((photoacid photo-acid photo adj acid)	DERWENT	
	_	adj2 generator) pag!)		
-	0	(((antihalation anti-halation anti adj	USPAT;	2003/05/20 14:50
		halation)) same (resin adj binder) same (acid (thermal adj2 generator)) same	US-PGPUB;	
		(((photoacid photo-acid photo adj acid)	EPO; JPO; DERWENT	
		adj2 generator) pag!)) not	DERWENT	
		((((antireflective antireflection		
		anti-reflective anti-reflection anti adj		
		reflective anti adj reflection) (tarc!		
!		barc!) ((arc!) near (coating film layer	1.	
		material))) same (resin adj binder) same		
		((acid adj generator) (thermal adj2 generator)) same (((photoacid photo-acid		
		photo adj acid) adj2 generator) pag!))		
		(((antireflective antireflection		
		anti-reflective anti-reflection anti adj		
į į		reflective anti adj reflection) (tarc!		
		barc!) ((arc!) near (coating film layer		
		material))) same (resin adj binder) same		
		<pre>(acid (thermal adj2 generator)) same (((photoacid photo-acid photo adj acid)</pre>	}	
		adj2 generator) pag!)))		
_	11	(("4362809") or ("4370405") or ("4910122")	USPAT;	2003/05/20 14:54
		or ("4576898") or ("4060656") or	US-PGPUB	
		("5541037") or ("5669784") or ("5886102")		
		or ("5851730") or ("5756255") or		
	2	("5635333")).PN. ((("4362809") or ("4370405") or	HCDAM.	2002/05/20 15:01
-	2	((("4362809") or ("4370405") or ("4060656")	USPAT; US-PGPUB;	2003/05/20 15:01
	·	or ("5541037") or ("5669784") or	EPO; JPO;	
		("5886102") or ("5851730") or ("5756255")	DERWENT	
		or ("5635333")).PN.) and ((antireflective	·	
		antireflection anti-reflective		
]		anti-reflection anti adj reflective anti		
		adj reflection) (tarc! barc!) ((arc!)		
,		near (coating film layer material)) (antihalation anti-halation anti adj		
		halation)) and ((thermal adj2 generator)		
		acid) and (((photoacid photo-acid photo		
		adj acid) adj2 generator) pag!)		
-	2	ep-542008-\$.did.	USPAT;	2003/05/20 14:58
1			US-PGPUB;	1
			EPO; JPO; DERWENT	

_	2	wo-9003598-\$.did.	USPAT;	2003/05/20 14:59
			US-PGPUB;	
			EPO; JPO;	
			DERWENT	
_	2	wo-9322901-\$.did.	USPAT;	2003/05/20 15:01
	_	, , , , , , , , , , , , , , , , , , ,	US-PGPUB:	2000, 00, 20 10.01
			EPO; JPO;	
			DERWENT	
_	1	((("5851730") or ("5110697")).PN.) and	USPAT;	2003/05/20 15:03
	_	((antireflective antireflection	US-PGPUB;	=====================================
		anti-reflective anti-reflection anti adi	EPO; JPO;	
		reflective anti adj reflection) (tarc!	DERWENT	
		barc!) ((arc!) near (coating film layer	_	
		material)) (antihalation anti-halation		!
		anti adj halation)) and ((thermal adj2	:	
		generator) acid) and (((photoacid		
		photo-acid photo adj acid) adj2 generator)		
		pag!)		
-	4	(("5851730") or ("5110697")).PN.	USPAT;	2003/05/20 15:02
		'	US-PGPUB;	!
			EPO; JPO;	
			DERWENT	
-	4	((("5851730") or ("5110697")).PN.) and	USPAT;	2003/05/20 15:03
		(((antireflective antireflection	US-PGPUB;	
		anti-reflective anti-reflection anti adj	EPO; JPO;	
		reflective anti adj reflection) (tarc!	DERWENT	
		barc!) ((arc!) near (coating film layer		
		material)) (antihalation anti-halation		
		anti adj halation)) ((thermal adj2		
		generator) acid) (((photoacid photo-acid		
		photo adj acid) adj2 generator) pag!))		

DERWENT-ACC-NO:

1999-492970

DERWENT-WEEK:

200176

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TITLE:

Antireflective coating composition

for use with deep UV

photoresist in integrated circuit

manufacture

INVENTOR: DOCANTO, M; PAVELCHEK, E K

PATENT-ASSIGNEE: SHIPLEY CO LLC[SHIL]

PRIORITY-DATA: 1997US-0797741 (February 7, 1997)

PATENT-FAMILY:

PUB-NO PUB-DATE

LANGUAGE PAGES MAIN-IPC

US 5939236 A August 17, 1999 N/A

012 G03F 007/095

JP 11133618 A May 21, 1999 N/A

055 G03F 007/11

KR 98071125 A October 26, 1998 N/A

 $000 \quad C09D \quad 005/32$

APPLICATION-DATA:

PUB-NO APPL-DESCRIPTOR APPL-NO

APPL-DATE

US 5939236A N/A

1997US-0797741 February 7, 1997

JP 11133618A N/A

1998JP-0061845 February 6, 1998

KR 98071125A N/A

1998KR-0003372 February 6, 1998

INT-CL (IPC): C09D005/00, C09D005/32, G03F007/004,

G03F007/095,

G03F007/11

ABSTRACTED-PUB-NO: US 5939236A

BASIC-ABSTRACT:

NOVELTY - By incorporating a photoacid generator in the antireflective layer composition sufficient acid can be generated in the antireflective layer during exposure of the photoresist layer to compensate for diffusion or neutralization in the resist layer. As a result resist relief images having vertical profiles and with little footing can be produced.

DETAILED DESCRIPTION - Substrate coated with layers comprising:

- (a) Antireflective composition comprising; resin binder; acid or thermal acid generator; photoacid generator;
- (b) Photoresist comprising a resin and a photoacid generator.

An INDEPENDENT CLAIM also includes a substrate coated with:

- (a) Antireflective composition comprising resin binder and photoacid generator free of crosslinker component;
- (b) Chemically-amplified positive acting photoresist comprising a resin and a photoacid generator.

USE - Photolithographic processes for semiconductor device or integrated circuit manufacture, particularly using deep UV radiation.

ADVANTAGE - The antireflective composition reduces undesired notching and footing of an overcoated photoresist relief image.

CHOSEN-DRAWING: Dwg.0/0

TITLE-TERMS: ANTIREFLECTIVE COATING COMPOSITION DEEP ULTRAVIOLET PHOTORESIST

INTEGRATE CIRCUIT MANUFACTURE

DERWENT-CLASS: A89 G06 L03 P84 U11

A12-E07C; A12-L02B2; G06-A02; G06-D06; CPI-CODES: G06-F03C; L04-C06B; EPI-CODES: U11-C04A1H; ENHANCED-POLYMER-INDEXING: Polymer Index [1.1] 018 ; D01 D07 D21 D18 D33 D79 ; P0226 P0282*R D01 D18 F30 : P0497 P0464 P0226 P0282 M2175 D01 D18 ; M9999 M2175 ; M9999 M2073 ; M9999 M2095*R; K9858 K9847 K9790; L9999 L2391; L9999 L2095*R; M9999 M2391 ; M9999 M2186 Polymer Index [1.2] 018 ; D07 D25 D22 D79 D33 D41 F15 ; P0226 P0282*R D01 D18 F30 ; P0497 P0464 P0226 P0282 M2175 D01 D18 ; M9999 M2175 ; M9999 M2073 ; M9999 M2095*R ; K9858 K9847 K9790 ; L9999 L2391 ; L9999 L2095*R ; M9999 M2391 ; M9999 M2186 Polymer Index [1.3] 018 ; D01 D24 D22 D32 D78 D41 F15 F31 F30 ; P0226 P0282*R D01 D18 F30 ; P0497 P0464 P0226 P0282 M2175 D01 D18 ; M9999 M2175 ; M9999 M2073 ; M9999 M2095*R ; K9858 K9847 K9790 ; L9999 L2391 ; L9999 L2095*R ; M9999 M2391 ; M9999 M2186 Polymer Index [1.4] 018 ; ND01 ; Q9999 Q8684 Q8673 Q8606 ; Q9999 Q7476 Q7330 ; B9999 B4400*R B4240 ; Q9999 Q6791 ; B9999 B4988*R B4977 B4740 ; K9687 K9676; K9712 K9676; K9585 K9483; K9483*R Polymer Index [1.5] 018 ; R00760 G2028 D01 D11 D10 D19 D18 D31 D50 D60 D76 D87 F62 ; A999 A157*R Polymer Index [1.6] 018 ; D05 D16 D13 D19 D18 D34 D76 D77 D50 D61*R D95 F23 F62 I* 7A ; A999 A204 Polymer Index [2.1] 018 ; G1821*R D01 F78 D11 D10 D24 D22 D32 D77 D45 D50

D92 F34;
R00001 G1503 D01 D50 D81 F22; A999 A782; A999 A157*R; P0259*R
P0226 D01; M9999 M2200

SECONDARY-ACC-NO:

CPI Secondary Accession Numbers: C1999-144398 Non-CPI Secondary Accession Numbers: N1999-367126 DERWENT-ACC-NO:

2002-291273

DERWENT-WEEK:

200253

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TITLE:

Anti-reflective coating composition

for deep ultraviolet

application contains resin binder and

photoacid generator

INVENTOR: DOCANTO, M ; PAVELCHEK, E K

PATENT-ASSIGNEE: SHIPLEY INC[SHIL] , SHIPLEY CO LLC[SHIL]

PRIORITY-DATA: 2000US-0616851 (July 14, 2000),

2001US-0904587 (July 14, 2001)

, 2000US-0685750 (October 10, 2000)

PATENT-FAMILY:

PUB-NO PUB-DATE

LANGUAGE PAGES MAIN-IPC

US 20020012875 A1 January 31, 2002 N/A

012 G03F 007/26

CN 1347932 A May 8, 2002 N/A

000 C08J 005/00

KR 2002007135 A January 26, 2002 N/A

000 C08J 009/22

APPLICATION-DATA:

PUB-NO APPL-DESCRIPTOR APPL-NO

APPL-DATE

US20020012875A1 Div ex

2000US-0616851 July 14, 2000

US20020012875A1 N/A

2001US-0904587 July 14, 2001

CN 1347932A N/A

2001CN-0117235 March 27, 2001

KR2002007135A N/A

2001KR-0014871 March 22, 2001

INT-CL (IPC): C08J005/00, C08J009/22, C08L083/00,

G03F007/26

RELATED-ACC-NO: 2001-662161

ABSTRACTED-PUB-NO: US20020012875A

BASIC-ABSTRACT:

NOVELTY - An anti-reflective coating composition consists of resin binder, acid or thermal acid generator, and photoacid generator.

DETAILED DESCRIPTION - INDEPENDENT CLAIMS are also included for (A) a coated substrate and (B) formation of photoresist relief image. The substrate comprises a coating layer of the inventive composition and a coating layer of a photoresist. The photoresist relief image is formed by sequentially applying on a substrate, a layer of the inventive coating composition and a layer of photoresist composition, exposing the photoresist layer to activating radiation, and developing the exposed photoresist layer.

USE - For deep ultraviolet application.

ADVANTAGE - The inventive composition effectively reduces undesired footing or notching of an overcoated photoresist relief image.

CHOSEN-DRAWING: Dwg.0/0

TITLE-TERMS: ANTI REFLECT COATING COMPOSITION DEEP ULTRAVIOLET APPLY CONTAIN
RESIN BIND GENERATOR

DERWENT-CLASS: A14 A25 A26 A85 A89 G06 L03 P84 U11

CPI-CODES: A08-M08; A12-L02; G06-D04; G06-F03C; G06-F03D;

EPI-CODES: U11-A05; U11-A06A; U11-C04A1H;

ENHANCED-POLYMER-INDEXING:

Polymer Index [1.1]

018 ; G0419 G0384 G0339 G0260 G0022 D01 D12 D10 D26 D51 D53 D58

05/20/2003, EAST Version: 1.03.0002

D63 F41 F89 D07 D11 D21 D18 D33 D79 D94 ; R01463 G0408 G0384 G0339 G0260 G0022 D01 D11 D10 D12 D26 D51 D53 D58 D63 D86 F27 F26 F41 F89 ; H0022 H0011 ; S9999 S1627 S1605 ; P0088 Polymer Index [1.2] 018; 09999 07114*R; 09999 06791; B9999 B4422 B4400 B4240 ; Q9999 Q8684 Q8673 Q8606 ; K9483*R ; K9676*R ; ND01 Polymer Index [1.3] 018 ; D01 D11 D10 D50 D84 F27 F26 F34 ; A999 A475 Polymer Index [1.4] 018 ; D01 F07*R ; A999 A157*R Polymer Index [1.5] 018 ; D01 D11 D10 D19 D18 D31 D76 D50 D60 F62 F75 ; A999 A748 Polymer Index [1.6] 018 ; D01 D11 D10 D16 D13 D19 D18 D34 D95 F62 D69 I* 7A ; A999 A748

SECONDARY-ACC-NO:

CPI Secondary Accession Numbers: C2002-085391 Non-CPI Secondary Accession Numbers: N2002-227422

05/20/2003, EAST Version: 1.03.0002